



0321.68095

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Yeshaiahu Fainman
Serial No.: 10/521,425
Conf. No.: 9057
Filed: 3/22/2005
For: HOLOGRAPHICALLY DEFINED
SURFACE MASK ETCHING
METHOD AND ETCHED OPTICAL
STRUCTURES
Art Unit: 2814
Examiner: Rao, Shrinivas H.

I hereby certify that this paper is being deposited with the United States Postal Service as FIRST-CLASS mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on this date.

8/7/07 Al F. R
Date Registration No. 43,874
F-CLASS.WCM
Appr. February 20, 1998 Attorney for
Applicant(s)

AMENDMENT A

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

This is in response to the Office Action mailed May 7, 2007.